ASN O I P	C SOS IN	1 THE	UNITED STATES PATENT AND TR	ADEMARK OFFICE
TA TRADI	pplicant	:	ASM MICROCHEMISTRY OY)
	App. No.	:	See Appendix A)
	Filed	:	See Appendix A)
	For	:	See Appendix A)
•	Examiner	:	Unknown)

ESTABLISHMENT OF RIGHT OF ASSIGNEE TO TAKE ACTION AND REVOCATION AND POWER OF ATTORNEY

Commissioner for Patents P.O. Box 1450 Alexandria, VA 22313-1450

Dear Sir:

The undersigned is empowered to act on behalf of the assignee below (the "Assignee") with regard to the issued U.S. Patents and the U.S. Patent Applications listed on Appendix A, attached hereto. For each patent or patent Application listed in Appendix A the original Assignment(s) from the Inventors to ASM Microchemistry OY is recorded at the Reel and Frame numbers indicated or is attached. A true copy of the original Assignment of all listed patents and patent applications from ASM Microchemistry OY to the Assignee is also attached hereto and was submitted to the Assignment Division of the Office on December 17, 2003. This represents the entire chain from the Inventor(s) to the Assignee.

I declare that all statements made herein are true, and that all statements made upon information and belief are believed to be true, and further, that these statements were made with the knowledge that willful, false statements and the like so made are punishable by fine or imprisonment, or both, under 18 U.S.C. § 1001, and that willful, false statements may jeopardize the validity of the application, or any patent issuing thereon.

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The undersigned hereby revokes any previous powers of attorney in the subject application, and hereby appoints the registrants of Knobbe, Martens, Olson & Bear, LLP, 2040 Main Street, Fourteenth Floor, Irvine, California 92614, Telephone (949) 760-0404, Customer No. 20,995, as its attorneys with full power of substitution and revocation to prosecute this application and to transact all business in the U.S. Patent and Trademark Office connected herewith. This appointment is to be to the exclusion of the inventor(s) and his attorney(s) in accordance with the provisions of 37 C.F.R. § 3.71.

Please use Customer No. 20,995 for all communications.

ASM INTERNATIONAL N.V.

Dated: 18 Feb. 2004

Menso Hendriks

Title: Central IP Officer

Address: Jan van Eycklaan 10

3723 BC Bilthoven THE NETHERLANDS

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APPENDIX A

App. No.	Filing Date	Attorney Docket No.	Title	Patent No.	Assignment
	为了一 说 的看。		April 18 Charles Land Charles Land Charles Land		<u> </u>
			ing Tariff Care Substitute Washing		Inventors to
					ASM Microchem.
					Reel/Frame
00/696 613	1/4/00	SEPP1.001CP1	METHOD AND APPARATUS FOR	6,630,030	011650/0441
09/686,613	1/4/00	SEPPI.001CPI	GROWING THIN FILMS	0,030,030	011030/0441
09/581,020	6/7/00	SEPP2.001APC	METHOD FOR COATING INNER	6,416,577	010951/0586
09/381,020	6///00	SEPP2.001APC	SURFACES OF EQUIPMENT	0,410,377	010931/0380
09/619,820	7/20/00	SEPP4.001AUS	METHOD FOR REMOVING	6,506,352	011694/0504
09/019,820	//20/00	SEPP4.001AUS	SUBSTANCES FROM GASES	0,500,552	011094/0304
09/687,355	10/13/00	SEPP5.001AUS	METHOD FOR GROWING THIN	6,632,279	011557/0134
09/087,333	10/13/00	SEFF 5.00 INOS	OXIDE FILMS	0,032,279	011557/0154
09/749,339	12/27/00	SEPP6.001AUS	APPARATUS FOR GROWING THIN	6,551,406	011670/0177
05/145,555	12/27/00	BBIT 0.0011100	FILMS	0,551,100	01107070177
09/749,329	12/27/00	SEPP7.001AUS	APPARATUS FOR GROWING THIN	6,447,607	011670/0191
05,7,15,522	12/2//00		FILMS		
09/764,692	1/18/01	SEPP8.001AUS	PROCESS FOR GROWING	6,599,572	011484/0029
,			METALLOID THIN FILMS UTILIZING	, ,	
	•		BORON-CONTAINING REDUCING		
			AGENTS		
09/835,737	4/16/01	SEPP10.001AUS	PROCESS FOR PRODUCING OXIDE	6,548,424	012167/0702
			THIN FILMS		
09/800,757	3/6/01	ASMMC.002AUS	METHOD OF FORMING GRADED	6,534,395	011798/0754
	·		THIN FILMS USING ALTERNATING		
			PULSES OF VAPOR PHASE		
			REACTANTS		
09/843,518	4/26/01	ASMMC.004AUS	PROTECTIVE LAYERS PRIOR TO	6,482,733	011766/0345
			ALTERNATING LAYER DEPOSITION		01100000
09/791,167	2/22/01	ASMMC.007AUS	METHOD OF FORMING ULTRATHIN	6,492,283	011953/0233
00/660 077	6/10/00	+ G) O (G) 010 + V(G)	OXIDE LAYER	6.560.140	011052/0202
09/568,077	5/10/00	ASMMC.012AUS	APPARATUS FOR FABRICATION OF THIN FILMS	6,562,140	011053/0323
09/769,562	1/25/01	ASMMC.012C1	APPARATUS FOR FABRICATION OF	6,579,374	011053/0323
09//09,362	1/25/01	ASIMIMO.012C1	THIN FILMS	0,3/9,3/4	011033/0323
09/687,204	10/13/00	ASMMC.026AUS	DEPOSITION OF TRANSITION	6,482,262	011505/0816
09/3/67,204	10/13/00	ASIVIIVIC.020AUS	METAL CARBIDES	0,702,202	011303/0010
09/687,205	10/13/00	ASMMC.027AUS	PRODUCTION OF ELEMENTAL THIN	6,475,276	011505/0800
02/00/,203	10/15/00	1101/11/10.02/1100	FILMS USING A BORON-	0,175,270	011303/0000
			CONTAINING REDUCING AGENT		
L	<u> </u>	1	John Million Control No Property	L	L

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					4. <u>from</u> , k
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					Microchem.
10-10-10	Water Will	AND WATER OF THE PARTY OF THE P	a the constant part of the second second		Reel/Frame
10/205,296	7/24/02	SEPP4.001C1	METHOD AND APPARATUS FOR	Pending	011694/0504
			REMOVING SUBSTANCES FROM		

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4.4.4					from
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			Karata Andrewski	1 2 2 × 3 ×	<u>ASM</u>
					Microchem.
			GASES		Reel/Frame:
10/619 420	7/10/03	SEPP5.001C1	<u> </u>	Danding	011557/0134
10/618,429		*	METHOD FOR GROWING THIN OXIDE FILMS	Pending	
10/365,926	2/13/03	SEPP6.001DV1	APPARATUS FOR GROWING THIN FILMS	Pending	011670/0177
-10/205,297	7/24/02	SEPP7.001DV1	APPARATUS FOR GROWING THIN FILMS	Pending	011670/0191
10/394,309	3/20/03	SEPP8.001C1	PROCESS FOR GROWING METAL OR METAL CARBIDE THIN FILMS UTILIZING BORON-CONTAINING REDUCING AGENTS	Pending	011484/0029
09/787,062	6/28/01	SEPP9.001APC	METHOD FOR GROWING OXIDE	Pending	011938/0097
021707,002	0/20/01	5217.00111	THIN FILMS CONTAINING BARIUM AND STRONTIUM	1 0	011756,007,
09/836,674	4/16/01	SEPP11.001AUS	METHOD AND APPARATUS OF GROWING A THIN FILM ONTO A SUBSTRATE	Pending	012088/0322
10/270,745	10/11/02	SEPP11.001CP1	METHOD AND APPARATUS OF GROWING A THIN FILM	Pending	012088/0322
09/835,931	4/16/01	SEPP12.001AUS	METHOD OF GROWING A THIN FILM ONTO A SUBSTRATE	Pending	012029/0763
09/854,706	5/14/01	SEPP14.001AUS	METHOD AND APPARATUS FOR FEEDING GAS PHASE REACTANT INTO A REACTION CHAMBER	Pending	011811/0406
10/003,749	10/23/01	SEPP15.001AUS	PROCESS FOR PRODUCING ALUMINUM OXIDE FILMS AT LOW TEMPERATURES	Pending	012360/0374
10/066,315	1/29/02	SEPP16.001AUS	PROCESS FOR PRODUCING METAL THIN FILMS BY ALD	Pending	012950/0394
10/067,634	2/4/02	SEPP17.001AUS	METHOD OF DEPOSITING RARE EARTH OXIDE THIN FILMS	Pending	012573/0185 and 012913/0230
10/100,500	3/15/02	SEPP18.001AUS	METHOD FOR PREPARING METAL NITRIDE THIN FILMS	Pending	012711/0064
10/110,598	4/11/02	SEPP19.001APC	METHOD OF MODIFYING SOURCE CHEMICALS IN AN ALD PROCESS	Pending	013027/0564
10/110,730	4/11/02	SEPP20.001APC	METHOD OF DEPOSITING TRANSITION METAL NITRIDE THIN FILMS	Pending	013038/0940
10/148,525	8/27/02	SEPP21.001APC	METHOD OF GROWING OXIDE FILMS	Pending	013005/0964
10/276,663	11/15/02	SEPP22.001APC	PROCESS FOR PRODUCING INTEGRATED CIRCUITS	Pending	Copy Attached
10/333,521	1/17/03	SEPP23.001APC	METHOD OF GROWING A THIN FILM ONTO A SUBSTRATE	Pending	013967/0142
10/253,859	9/23/02	ASMMC.002C1	GRADED THIN FILMS	Pending	011798/0754
10/329,658	12/23/02	ASMMC.002DV1	GRADED THIN FILMS	Pending	011798/0754
10/237,526	9/6/02	ASMMC.004DV1	PROTECTIVE LAYERS PRIOR TO	Pending	011766/034%

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				Alle FOR CO.	<u>from</u>
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			and the second section is a second section.		Microchem. Reel/Frame
	8 12 20 E		ALTERNATING LAYER DEPOSITION		Reel/Frame
10/202 255	11/21/02	A CMMC ADVICT	<u> </u>	Donding	011766/0345
10/303,355	11/21/02	ASMMC.4DV1C1	METHOD FOR CONTROLLING CONFORMALITY WITH	Pending	011/00/0343
	Ì		ALTERNATING LAYER DEPOSITION		
10/303,293	11/22/02	ASMMC.4DV1CP1	SEALING POROUS STRUCTURES	Pending	013888/0070
£0/303,293 £09/887,199	6/21/01	ASMMC.005AUS	METHOD OF FABRICATING	Pending	013888/0070
109/86/,199	0/21/01	ASIMIMIC.003AUS	TRENCH ISOLATION STRUCTURES	rending	01247270073
	1		FOR INTEGRATED CIRCUITS USING		
v]		ATOMIC LAYER DEPOSITION	•	
10/049,125	2/7/02	ASMMC.008APC	METHOD FOR DEPOSITING	Pending	013209/0629
10/049,123	2/1/02	ASIMINO.000AT C	NANOLAMINATE THIN FILMS ON	Chaing	01520570025
			SENSITIVE SURFACES		
10/383,291	3/6/03	ASMMC.012C2	APPARATUS FOR FABRICATION OF	Pending	011053,0323
10/303,271	370703	7151411410.01202	THIN FILMS	1 chaing	011055,0525
09/997,396	11/28/01	ASMMC.020AUS	THIN FILMS FOR MAGNETIC	Pending	012562/0145
03,337,330	11,20,01	1101111010201102	DEVICE		
10/246,131	9/17/02	ASMMC.026C1	DEPOSITION OF TRANSITION	Pending	011505/0816
			METAL CARBIDES		
10/210,715	7/30/02	ASMMC.027C1	PRODUCTION OF ELEMENTAL	Pending	011505/0800
,			FILMS USING A BORON-		
			CONTAINING REDUCING AGENT		
09/945,463	8/31/01	ASMMC.029AUS	METHODS FOR MAKING A	Pending	012303/0047
ŕ			DIELECTRIC STACK IN AN		
			INTEGRATED CIRCUIT		
10/653,737	9/2/03	ASMMC.029DV1	METHODS FOR MAKING A	Pending	012303/0047
			DIELECTRIC STACK IN AN		
	Market II	beauties a distribute.	INTEGRATED CIRCUIT		Liberary .
09/801,542	3/7/01	ASMMC.030AUS	ALD REACTOR AND METHOD WITH	Pending	011610/0908
			CONTROLLED WALL		
			TEMPERATURE		4
10/227,475	8/22/02	ASMMC.031AUS	LOW TEMPERATURE METHOD OF	Pending	013897/0346
•	1		FORMING A GATE STACK WITH A		
			HIGH K LAYER DEPOSITED OVER		l)
	13.11.11		AN INTERFACIAL OXIDE LAYER		
10/136,095	4/30/02	ASMMC.032AUS	METHOD OF DEPOSITING THIN	Pending	013660/0588
			FILMS FOR MAGNETIC HEADS		
10/007,304	12/5/01	ASMMC.033AUS	COPPER INTERCONNECT	Pending	012874/0783
			STRUCTURE HAVING STUFFED		·
			DIFFUSION BARRIER		
10/066,169	1/30/02	ASMMC.034AUS	ACTIVE PULSE MONITORING IN A	Pending	012570/0319
			CHEMICAL REACTOR		
10/187,142	6/28/02	ASMMC.035AUS	SOURCE CHEMICAL CONTAINER	Pending	013369/0749
00.10==================================	101015		ASSEMBLY		
09/975,466	10/9/01	ASMMC.036AUS	IN SITU REDUCTION OF COPPER	Pending	012382/0183
	1		OXIDE PRIOR TO SILICON CARBIDE		and
10/222 225	0/14/02	A CIMO ACC COST A TYC	DEPOSITION A TOMOGRAPH A TOMOG	Don 11	012644/0307
10/222,005	8/14/02	ASMMC.037AUS	ATOMIC LAYER DEPOSITION	Pending	013590/0973
	1	<u></u>	REACTOR	L	

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1. 1. 1. 1. 1.		30 T 1 39 14 14			(from
H. Santa China and					Inventors to
					<u>ASM</u>
					Microchem. Reel/Frame
10/242,368	9/12/02	ASMMC.038AUS	METAL NITRIDE DEPOSITION BY	Pending	013590/0968
10/242,300	3/12/02	110111110.0507100	ALD WITH REDUCTION PULSE	1 chang	013370/0700
10/285,348	10/30/02	ASMMC.042AUS	METHOD OF MONITORING	Pending	013788/0317
			EVAPORATION RATE OF SOURCE		·
			MATERIAL IN A CONTAINER		

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